

Hermes-Epitek opens base in Kumamoto, Japan to accelerate local supply chain layout

Hermes-Epitek's new office base in Kumamoto, Japan, was officially opened on April 15, 2024. Hermes-Epitek Japan held an opening ceremony in the newly-built office this afternoon. It was kicked off by C.Y. Shu, Vice Chairman of Hermes-Epitek, and David Chen, President of Hermes-Epitek. Guests included Frank Hsieh, Representative of the Taipei Economic and Cultural Representative Office in Japan, and Kimura Takashi, Governor-elect of Kumamoto Prefecture and a number of local business partners.

In response to customer demand and Japan's proactive revival of the semiconductor industry, Hermes-Epitek decided to establish its first base in Kyushu, Japan in 2022. In addition to supporting long-term customers, Hermes-Epitek is also working hard to expand cooperation opportunities in Japan, including for manufacturing of compound semiconductors, such as silicon carbide (SiC), and advanced packaging.

Advanced Ion Beam Technology, Inc. (AIBT), a subsidiary of Hermes-Epitek, has continuously developed and produced low-energy, high-current ion implanters for more than 20 years, and jointly promoted two-nanometer process equipment with the largest advanced process customer in semiconductors. AIBT has since become a key manufacturer of front-end semiconductor process equipment in Taiwan. AIBT's iBlazar adopts the industry standard, Linear Scan. By integrating the latest technology, ISO Scan, and high-performance wafer transfer system, iBlazar has excellent particle defect control and high vacuum performance.

SiC has high voltage and high current characteristics. It is particularly suitable for the upcoming electric vehicle applications. Japan is a traditional automobile manufacturing country, and Hermes-Epitek plans to create more cooperation opportunities in the Japanese automotive electronics market. In the compound semiconductor supply chain, Hermes-Epitek currently has a complete layout. Ranging from SiC boule, substrate manufacturing (SiC substrate), research and development of EPI process equipment (SiC EPI CVD), to testing solutions, Hermes-Epitek works to become a stable supplier and



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partner to major international automobile manufacturers.

About Hermes-Epitek

Hermes-Epitek was founded in 1977. We started as a semiconductor equipment agent and have been endeavoring on research and development of proprietary equipment, and forward-looking technology, so that we are able to provide customers with first-class products and services. For more than 40 years, Hermes-Epitek has worked with many major semiconductor equipment manufacturers, and has successfully developed equipment such as the ICP Etcher, Ion Beam Implanter, and Metal-Organic Chemical Vapor Deposition (MOCVD), and is deeply involved in the production of chemical compound materials, and mass production of silicon carbide substrates (SiC substrates). Hermes-Epitek's service bases are located in Taiwan, the United States, Japan, Singapore, Malaysia and Mainland China, with a total of more than 1,200 employees. For more information, please refer to the official website:

<https://www.hermes.com.tw/>.

Press contact:

Janice Liao +886 911 121899 Janice.Liao@hermes.com.tw